

Application Data Sheet

Application Information

Application number::
Filing Date::
Application Type:: Regular
Subject Matter:: Utility
Title :: LASER IRRADIATION
APPARATUS, LASER
IRRADIATION METHOD,
AND METHOD FOR
MANUFACTURING A
SEMICONDUCTOR DEVICE
Attorney Docket Number:: 0756-7263
Total Drawing Sheets:: 16
Small Entity?:: No

Applicant Information

Applicant Authority Type:: Inventor
Primary Citizenship Country:: Japan
Given Name:: Shunpei
Middle Name::
Family Name:: YAMAZAKI
Name Suffix::
City of Residence:: Setagaya
State or Province of Residence:: Tokyo
Country of Residence:: Japan

Street of mailing address:: c/o Semiconductor Energy
Laboratory Co., Ltd.
398, Hase
Atsugi-shi
Kanagawa-ken
Japan
Postal or Zip Code of mailing address:: 243-0036

Applicant Authority Type:: Inventor
Primary Citizenship Country:: Japan
Given Name:: Koichiro
Middle Name::
Family Name:: TANAKA
Name Suffix::
City of Residence:: Atsugi-shi
State or Province of Residence:: Kanagawa-ken
Country of Residence:: Japan
Street of mailing address:: c/o Semiconductor Energy
Laboratory Co., Ltd.
398, Hase
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Postal or Zip Code of mailing address:: 243-0036

Correspondence Information

Correspondence Customer Number :: 31780
E-Mail address:: erobinson@ripl.com

Representative Information

Representative Customer Number:: 31780

Domestic Priority Information

Application ::	Continuity Type::	Parent Application::	Parent Filing Date::

Foreign Priority Information

Country::	Application number::	Filing Date::	Priority Claimed::
Japan	2003-071608	03/17/2003	Yes

Assignee Information

Assignee name:: Semiconductor Energy
Laboratory Co., Ltd.
Street of mailing address:: 398 Hase
City of mailing address:: Atsugi-shi
State or Province of mailing address:: Kanagawa-ken
Country of mailing address:: Japan
Postal or Zip Code of mailing address:: 243-0036